

<b>INFORMATION DISCLOSURE CITATION IN AN APPLICATION</b> (PTO-1449)		ATTY. DOCKET NO. 006301 USA/ Consilium/Consilium	SERIAL NO. 09/928,474			
		APPLICANT Badri N. KRISHNAMURTHY et al.				
		FILING DATE August 14, 2001	GROUP 2812			
<b>U.S. PATENT DOCUMENTS</b>						
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
<i>AG</i>	4,974,543	12/04/90	Jansen			02/28/86
	5,621,241	04/15/97	Jain			06/07/95
	5,660,895	08/26/97	Lee et al.			04/24/96
	5,874,345	02/23/99	Coronel et al.			11/18/96
	5,937,323	08/10/99	Orczyk et al.			06/03/97
	6,201,208 B1	03/13/01	Wendt et al.			11/04/99
	6,217,658 B1	04/17/01	Orczyk et al.			06/09/99
	6,232,236 B1	05/15/01	Shan et al.			08/03/99
	6,373,033 B1	04/16/02	Waard et al.			06/27/00
<b>FOREIGN PATENT DOCUMENTS</b>						
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation
						Yes
<i>AG</i>	WO 01/01205 A2	01/04/01	WIPO			X
<i>AG</i>	GB 2 363 477 A	12/19/01	United Kingdom			X
<b>OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)</b>						
<i>AG</i>	Rauf, Shahid and Mark J. Kushner. August 1998. "Virtual Plasma Equipment Model: A Tool for Investigating Feedback Control in Plasma Processing Equipment." <i>IEEE Transactions on Semiconductor Manufacturing</i> . Vol. 11, No. 3. pp. 486-494.					
	Rauf, Shahid and Mark J. Kushner. May/June 1999. "Controller design issues in the feedback control of radio frequency plasma processing reactors." <i>J. Vac. Sci. Technol. A</i> . Vol. 17, No. 3. pp. 704-712.					
	Cruden, Brett et al. "Chemical Vapor Deposition (CVD) of Teflon & trade-like Films for Use in Low-k Interlayer Dielectric Applications." <a href="http://plasma-processing.com/chemvap">http://plasma-processing.com/chemvap</a> .					
	Kim, Jiyoun et al. "Gradient and Radial Uniformity Control of a CMP Process Utilizing a Pre-and Post-Measurement Strategy." <i>University of Michigan, Electrical Engineering and Computer Science Department</i> .					
	November 11, 2004. International Search Report for PCT Serial No. PCT/US03/36501.					
EXAMINER <i>Andrea C</i>	DATE CONSIDERED <i>05-16-05</i>					

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

<b>INFORMATION DISCLOSURE CITATION IN AN APPLICATION</b>  <b>(PTO-1449)</b>		ATTY. DOCKET NO. 006301 USA/Consilium/Consilium	SERIAL NO. 09/928,474				
		APPLICANT Badri N. KRISHNAMURTHY et al.					
		FILING DATE August 14, 2001	GROUP 2812				
<b>FOREIGN PATENT DOCUMENTS</b>							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
<i>DR</i>	0 397 924 A1	11/22/90	Europe			X	
<b>OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)</b>							
<p><i>DR</i></p> <p>Rocha, Joao and Carlos Ramos. September 12, 1994. "Task Planning for Flexible and Agile Manufacturing Systems." <i>Intelligent Robots and Systems '94. Advanced Robotic Systems and the Real World, IROS '94. Proceedings of the IEEE/RSJ/GI International Conference on Munich, Germany 12-16 Sept. 1994.</i> New York, New York: IEEE. pp. 105-112.</p> <p>March 15, 2002. Office Action for U.S. Serial No. 09/469,227, filed December 22, 1999.</p> <p>March 29, 2002. Office Action for U.S. Serial No. 09/363,966, filed July 29, 1999.</p> <p>June 20, 2002. Office Action for U.S. Serial No. 09/619,044, filed July 19, 2000.</p> <p>September 26, 2002. Office Action for U.S. Serial No. 09/637,620, filed August 11, 2000.</p> <p>October 23, 2002. Office Action for U.S. Serial No. 09/469,227, filed December 22, 1999.</p> <p>December 17, 2002. Office Action for U.S. Serial No. 09/363,966, filed July 29, 1999.</p> <p>February 10, 2003. Office Action for U.S. Serial No. 09/619,044, filed July 19, 2000.</p> <p>May 8, 2003. Office Action for U.S. Serial No. 09/637,620, filed August 11, 2000.</p> <p>June 18, 2003. Office Action for U.S. Serial No. 09/655,542, filed September 6, 2000.</p> <p>August 8, 2003. International Search Report for PCT/US03/08513.</p> <p>August 25, 2003. Office Action for U.S. Serial No. 10/100,184, filed March 19, 2002.</p> <p>November 5, 2003. Office Action for U.S. Serial No. 10/172,977, filed June 18, 2002.</p> <p>December 1, 2003. Office Action for U.S. Serial No. 10/173,108, filed June 18, 2002.</p> <p>December 11, 2003. Office Action for U.S. Serial No. 09/943,383, filed August 31, 2001.</p> <p>December 16, 2003. International Search Report for PCT/US03/23964.</p> <p>January 20, 2004. Office Action for U.S. Serial No. 09/927,444, filed August 13, 2001.</p> <p>January 23, 2004. International Search Report for PCT/US02/24860.</p> <p>February 2, 2004. Office Action for U.S. Serial No. 09/363,966, filed July 29, 1999.</p>							
EXAMINER <i>André</i>				DATE CONSIDERED <i>7-15-05</i>			

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.